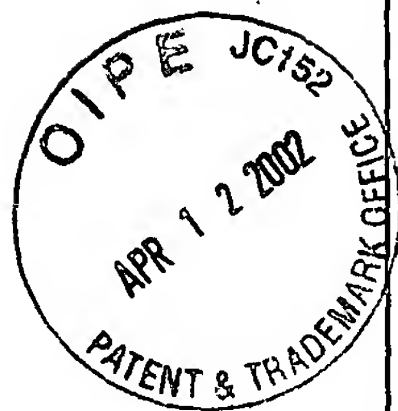


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of)
Kyoungdoug MIN., et al.)
Serial No. 10/084,622)
Filed: February 28, 2002)
For: METHOD OF THROUGH-ETCHING SUBSTRATE)

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

Under the provisions of 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicant submits herewith copies of the enclosed publications that the Office may wish to consider in examination of the subject application. The publications are also listed on the attached form PTO-1449.

Respectfully submitted,

By G. F. Rothwell
G. Franklin Rothwell
Attorney for Applicants
Registration No. 18,125
ROTHWELL, FIGG, ERNST & MANBECK, p.c.
Suite 800, 1425 K Street, N.W.
Washington, D.C. 20005
Telephone: (202)783-6040

Enclosures:
1751-300, IDS

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Complete Known

Application Number	10/084,622
Filing Date	February 28, 2002
First Named Inventor	Kyoungdoug MIN, et al.
Group Art Unit	
Examiner Name	
Attorney Docket Number	1751-300

Sheet 1 of 1

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
	1	A.A. AYON, et al., "Characterization of a Time Multiplexed Inductively Coupled Plasma Etcher", <u>Journal of the Electrochemical Society</u> , 1999, 339-349 pp., vol 146 (1), The Electrochemical Society, Inc., Cambridge, Massachusetts, USA.	
	2	LUC G. FRECHETTE, et al., "Demonstration of a Microfabricated High-Speed Turbine Supported on Gas Bearings", <u>Solid-State Sensor and Actuator Workshop Hilton Head Is., SC</u> , June 4-8, 2000, 1-5 pp., Gas Turbine Laboratory and Microsystems Technology Laboratories Massachusetts Institute of Technology, Cambridge, Massachusetts, USA.	
	3	RAVI KHANNA, et al., "Microfabrication Protocols for Deep Reactive Ion Etching and Wafer-Level Bonding", <u>MicroStrain Materials Science</u> , Sensors Online.	
	4	Amit Mehra, et al., " A Six-Wafer Combustion System for a Silicon Micro Gas Turbine Engine", <u>Journal of Microelectromechanical systems</u> , December 2000, 517-527pp, vol. 9, no. 4, IEEE.	
Examiner Signature		Date Considered	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.